

On-Demand Manufacturing of Electronics (ODME) APR: September 2023

Zach Courtright | ISM Portfolio Manager | FY23 ODME Annual Review Presentation | 09.22.23 zachary.s.courtright@nasa.gov



Why In-Space Manufacturing??



Reduce Launch Burden Related to Cargo Delivery to Space (image credit NASA)



Reduce launch mass through in-situ resource use (image credit ICON)

Moon to Mars Objectives (image credit Redwire)



Recycling and Trash Management (image credit NASA)

Bring



On-demand manufacturing of critical parts and tools

Recycle & Reuse



Build objects too big or fragile to launch

In-Situ Resource Utilization



In-Space Manufacturing Goals & Objectives



1) Develop a Space Economy

M2M Goal Supported: LI-4L, Demonstrate <u>advanced manufacturing</u> and autonomous construction capabilities in support of <u>continuous human lunar</u> <u>presence</u> and a <u>robust lunar economy</u>.

Applications: Manufacture goods for Government and Industry

- Leverage the microgravity environment
- Enable Outfitting of Habitats
- Manufacturing goods in space for Earth

Focus: AM/Welding of Metals, Polymers, Electronics, Logistics Reduction, Biomanufacturing, and Computational Modeling/Digital Twins





Printed Electronics



2) Enable Sustainable Deep Space Missions

M2M Goals Supported: LI-8L, Demonstrate technologies supporting cislunar orbital/surface depots, construction and manufacturing <u>maximizing the use of in-situ resources</u>, and support systems needed for <u>continuous human/robotic presence</u>; and TH-4LM, <u>Develop in-space and surface habitation system(s)</u> for crew to live in deep space for extended durations, enabling future missions to Mars.

Applications: Living Sustainably on the Lunar and Martian Surfaces

- Medical Devices
- Crew Tools & Engagement
- Habitats Outfitting & Infrastructure
- EVA Aids (ex. modular excursion devices)

Focus: Enabling living and working in space to be sustainable \rightarrow reducing operations cost.

FabLab (multimaterial printer for µg application)



Heat Exchangers

On Demand Cast



Fasteners and Tools

GCD FY23 Annual Program Review Takeaway: NASA is investing in the development of enabling manufacturing technologies for use in space.

Reformulation Preview – In Work



Techr	nology Development Needs Addressed by ODME	Acronyms:				
ESDMD/EC	Infusion of ODME tech for REALM RFID and ECLSS sensors	EC = Exploration Capabilities HRP = Human Research Program InSPA = In Space Production Applications BEALM = REID Enabled Autonomous Logistics Management				
SOMD/HRP	Infusion of ODME tech for biosensors and extreme environments					
SOMD/InSPA	Commercial infusion of ODME tech for semiconductors and microelectronics	926, 1065 1066,	RFID = Radio Frequency IDentification ECLSS = Environmental Control and Life Support Systems FQ = Flight Opportunities			
Project Goals						
Goal #1	Develop and integrate deposition systems for multilayer electronic devices through parabolic flight demonstrations culminating in an Interim Design Review (IDR).					
Goal #2	Develop and test the semiconductor manufacturing technologies and support parabolic flight testing to demonstrate critical functions.					
Project Objectives				Notes		
Objective #1	Development, ground testing, and support of parabolic flight testing for direct ink write process and applications including via filling and chip placement.	Parabolic Flights fund	rabolic Flights funded through FO			
Objective #2	Development and ground testing of the Electrohydrodynamic Inkjet materials and proce	GCD funds will target ground development maturing the technology through TRL 3-4				
		Parabolic Flights funded through FO and InSPA				
Objective #3	Conduct an Interim Design Review of an Integrated Printed Electronics Printer Module	Pending approval of continuation to IDR				
Objective #4	Demonstrate the feasibility of the printing of electronic devices by a Laser Ablation Deposition process.	Feasibility studies would target simple electronics printing; however, depending on testing results, active devices along with alloy deposition would be tested.				
Objective #5	Development of laser curing for dielectric and conductive inks through a laboratory gro demonstration.	Development of laser curing would be limited to the primary electronic feedstocks such as conductive and dielectric materials				

ISM ODME Project Organization



ODME Partnership Map



Exploration & Science

- NASA Exploration and Support "In Space for Space" development
- ECLSS Sensors
- Wearable sensors
- Printed Power & Energy
- Logistics spares and upgrades for missions

Commercialization Support "In Space for Earth Applications" development

Semiconductors



Academic

- University of Louisville
- University of Alabama Huntsville
- Appalachian State
- Auburn University
- Boise State
- Georgia Tech
- CalTech
- Iowa State University
- Florida A&M University
- Oregon State University
- West Virginia University

NASA Centers

- Marshall Space Flight Center
- Ames Research Center
- Kennedy Space Center
- Goddard Space Flight Center ٠
- Jet Propulsion Laboratory
- Glenn Research Center
- Langley Research Center
- Armstrong Flight Research Center

Industry/Government

- Techshot
- Redwire Space
- Cornerstone Research Group
- LambdaVision
- Faraday Incorporated
- Laboratory for Physical Sciences
- Intel

- •Youngstown State University •University of Wisconsin
- University of Wyoming
- •University of Delaware
- University of Texas El Paso
- Mississippi State
- •Arizona State University
- •University of Delaware
- Stanford University
- The Ohio State University
- University of Texas at El Paso

Fujifilm

Axiom Space

Goeppert

NextFlex

nScrypt

Multi3D

ISS National Lab

٠

٠

٠

٠

٠

- Johnson Space Center

ODME Leveraged Collaborations





Draft – based on previous draft plan. Reformulated chart in-work.

TRL Progression



FY23 Accomplishments – Advanced Toolplate Development



The ODME Advanced Toolplate is a major technology development for Multi-material 3D printing.

Process

Camera

View

Downward-facing Camera & UV Curing

- The new Advanced Toolplate is 40% the volume of the previous Toolplate.
- Generation 3 tools are 35% smaller than generation 2, <u>enabling a doubling in the number of</u> tools on the Toolplate from four (4) to eight (8), thus doubling the ODME process capability and minimizing crew time in changeovers.
- Development of the <u>Advanced Toolplate and</u> <u>integration with the ODME Print Module</u> was completed in July 2023.
- A parabolic flight campaign to test the Advanced Toolplate and new toolheads wa scheduled for August but has been rescheduled by the flight provider to October 2023. (Flight Opportunities Funded)
- New toolheads are also being developed for th Advanced Toolplate, including EHD inkjet (semiconductors) and Faraday electrodeposition (Phase II SBIR).



Laser curing tool

FY23 Accomplishments – Electrohydrodynamic Inkjet Development



10

ODME is working with academic partners to develop a next-generation <u>thin film deposition system for</u> <u>semiconductors and microelectronics</u>. (ODME-funded research on labor and materials development. Flight Opportunities funded hardware development.)

- EHD inkjet uses an electric field rather than piezoelectric force for very precise deposition. This system has the potential to advance thin film deposition SOA into the nanometer range.
- ODME and Flight Opportunities have already <u>completed two parabolic flight campaigns</u> (120 parabolas) of zero gravity testing of this system prior to FY23. Two additional campaigns are planned for FY23.
- ODME, with the University of Wisconsin and Sciperio, are developing a new EHD inkjet toolhead for the Advanced Toolplate.
- A parabolic flight campaign to test the Advanced Toolplate and new toolheads was scheduled for August but has been rescheduled by the flight provider to October 2023.

Target applications for infusion:

- <u>Semiconductors / commercialization</u>
- Microelectronics for future missions
- Sensors HRP and ECLSS



SPEC	DMP-2850 IJ (Industry Std)	EHD Inkjet	
Minimum feature size	30 microns	0.5 microns	
Ink viscosity	4-8 centipoise	0.1 - 500 centipoise	
Ink surface tension	28-32 dynes/cm	1 - 800 dynes/cm	
Droplet size	1pL - 10pL	0.1fL - 10pL	

FY23 Accomplishments – Multilayer Process Development



ODME is developing the capability to fabricate more <u>complex printed electronics comprising multiple</u> <u>layers on flexible and non-flexible substrates</u>. ODME has a collaborative project with Auburn University on this research. ODME and Auburn have made significant progress in the second year of their research on multilayer processing. <u>Complete</u>

- Development and evaluation of multiple multilayer deposition processes and materials.
- <u>Successful printing of a Multilayer flexible printed</u> <u>circuit board.</u>
- Demonstrated with a functional LED blinking circuit board.
- ODME and Sciperio also <u>developed and fabricated</u> <u>a functional multilayer CO₂ sensor.</u>

Target applications for infusion:

- Microelectronics for future missions
- Sensors HRP and ECLSS



Multilayer CO₂ sensor FDM thermoplastic printing Milling for surface roughness Chip picking & placing Chip securement Via filling Trace deposition



Multilayer functional blinking circuit

FY23 Accomplishments – Printed Semiconductor Development



Tech maturation through ODME development is a critical phase of commercialization of printed semiconductors. <u>ODME is collaborating with Intel, Axiom Space, TEL, Arizona State, and Univ. of</u> <u>Wisconsin to develop printed RERAM memory chips for microgravity production.</u> (ODME-funded research on labor and materials development. InSPA funding microgravity development by partner companies.)

- ODME EHD Inkjet process used to print nanocircuits of printed memory chips.
- The EHD process is significantly faster with much higher product yields, and it eliminated a secondary etch process required by current ground-based semiconductor fabrication.
- ODME and the Intel team have successfully demonstrated this technology on the ground in FY23, with a planned demonstration on parabolic flight testing in October.

Target applications for infusion:

• Semiconductors / commercialization



3-dimensional memory planned as demo printed electronic device for parabolic flights



 Combination of inkjet printing and µg offer high step coverage without voiding problem. Beneficial for 3D memory fabrication with high density and high performance Trench to be filled

SEADS = Space Enabled Advanced

Devices and Semiconductors





FY23 Accomplishments – Parabolic Flight Campaigns



- ODME Advanced Toolplate <u>testing of new Advanced Toolplate</u> and tools
- SEADS Semiconductors <u>testing of newly developed EHD inkjet process</u> for printing semiconductor memory chips (InSPA Funded)
- EHD Inkjet Integration into Advanced Toolplate testing of EHD inkjet head integrated into Advanced Toolplate

Target applications for infusion:

- Semiconductors / commercialization
- Microelectronics for future missions
- Sensors HRP and ECLSS

VALIDATION OF TECH DEVELOPMENT

GCD/ODME is Leveraging STMD Flight Opportunities investment into ODME tech maturation of microgravity technologies.





ODME Project Assessment Summary



	Performance			е	C ourse on to	
Project Name	С	S	Т	Ρ	Comments	
Mid-Year					 Technical is GREEN ODME and ODMM have finalized a technical approach on FabLab with Advanced Toolplate, using pooled resources. Task Order TO1 with TechShot has been updaated for ODME only, which includes Advanced Toolplate. Also, Flight Opportunities has approved funding for a new Parabolic Flight printer and support to test the Advanced Toolplate in May 2023. Cost is GREEN and within budget with the contract holds and cancellations from recent GCD budget impacts. Overall ODME collaborations and internal development have been reduced to align with reduced GCD budget. Schedule is GREEN ODMM and ODME have developed a new approach to the Advanced Toolplate with pooled available resources. GCD has re-funded the NextFlex project for development of flexible sensor platform. These delays have now been recovered in the schedule. Programmatic remains GREEN. 	
Annual					 Technical is GREEN. ODME is implementing a technical approach on the Advanced Toolplate. Flight Opportunities has also approved funding for a new Parabolic Flight printer and support to flight test the Advanced Toolplate in October 2023. <u>There may be risk going forward depending upon what path is chosen by GCD for ODME ISS orbital flight demonstration.</u> Cost is GREEN and within FY23 budget authority. Overall ODME collaborations and internal development have been reduced. Additional parabolic flight testing of the new Advanced Toolplate and EHD Inkjet/Semiconductors has been funded by Flight Opportunities and InSPA. Schedule is GREEN ODME is developing and parabolic flight testing the new Advanced Toolplate in October and November 2023. Programmatic remains GREEN. <u>Continuation Review for ODME successfully completed at MSFC on July 21. New Project Plan and TRAIT analysis will be completed after action items responses are approved by <u>GCD.</u></u> 	

ODME Plans Forward and Transition / Infusion Plan



Infusion/transition plan

 On-Demand Manufacturing of Electronics is a critical need for future habitats and missions. The technology infusion plan involves sub-orbital flight tests (MISEE, Sounding Rocket, Multiple Parabolic Flights). Elements of the technology are being developed FY21-24.

Exploration & Science Applicability

- Applicable to current ISS operations and planned CLD Phase Over
- Applicable to Artemis II, Lunar Surface Habitat
- Applicable to M2M and future exploration missions

ODME Project Summary



FY23 Project Collaborations

• ODME collaborates between 9 NASA Centers, 14 public or private companies, and 20 different universities.

Publications and EPO

- Published 17 collaborative research papers.
- Presented ODME project research at 4 conferences.
- Hosted MSFC visits for 10 of our external partners.
- The ODME team visited 4 academic or industry partners this year.

Summary of the TechMat Capability End State for the Scope of the Project • <u>The ODME project is developing technologies for the hardware required for on-demand</u> <u>electronics, sensors, and semiconductors in a microgravity environment.</u> To develop these technologies, ODME has engaged multiple research universities and private companies to collaborate in the development of the hardware, materials, and processes required for the microgravity demonstration on the ISS. <u>ODME is leading the tech development of new leading</u>edge technologies required for the manufacturing of semiconductors in space.